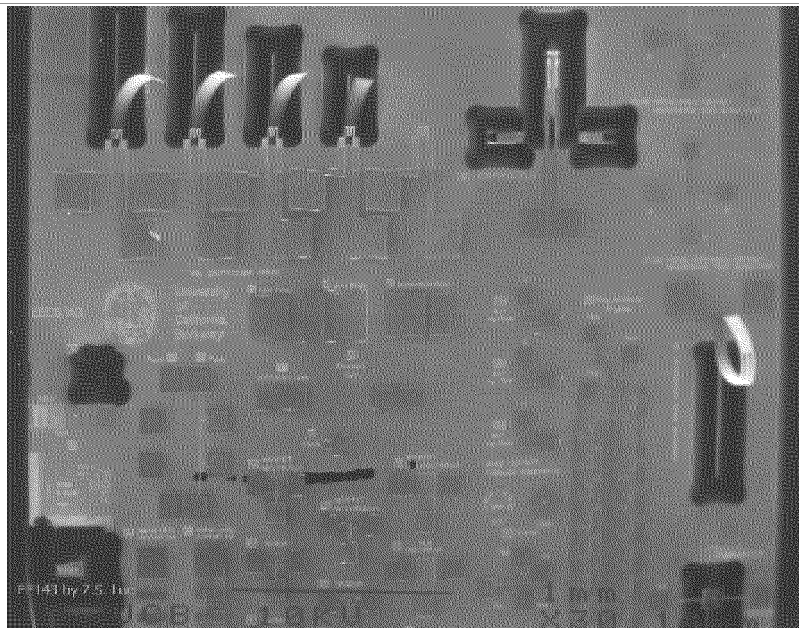
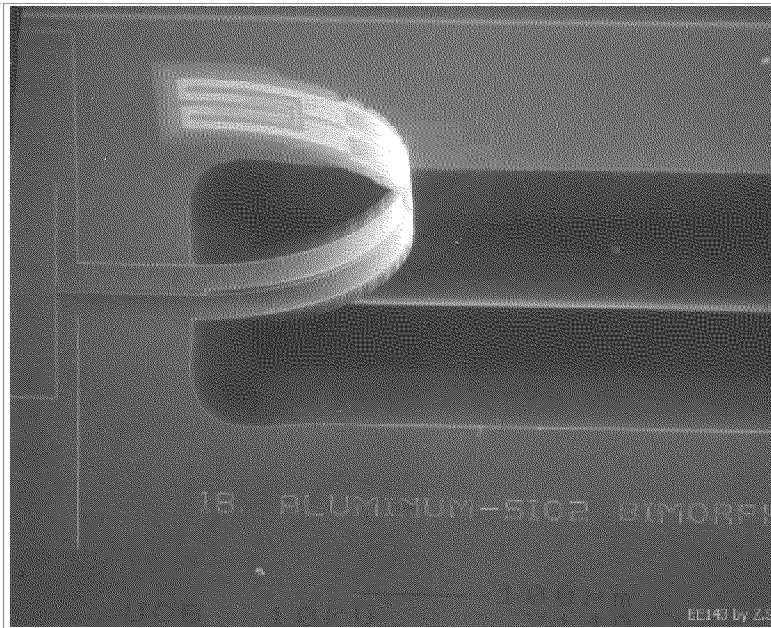


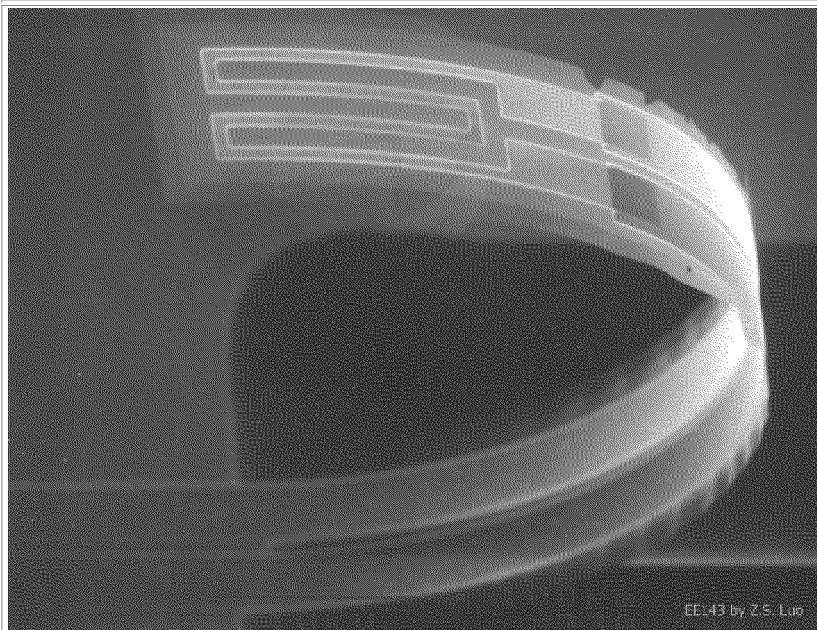
SEM (Scanning Electron Microscopy) Micrographs of EE143 MEMS Structures*



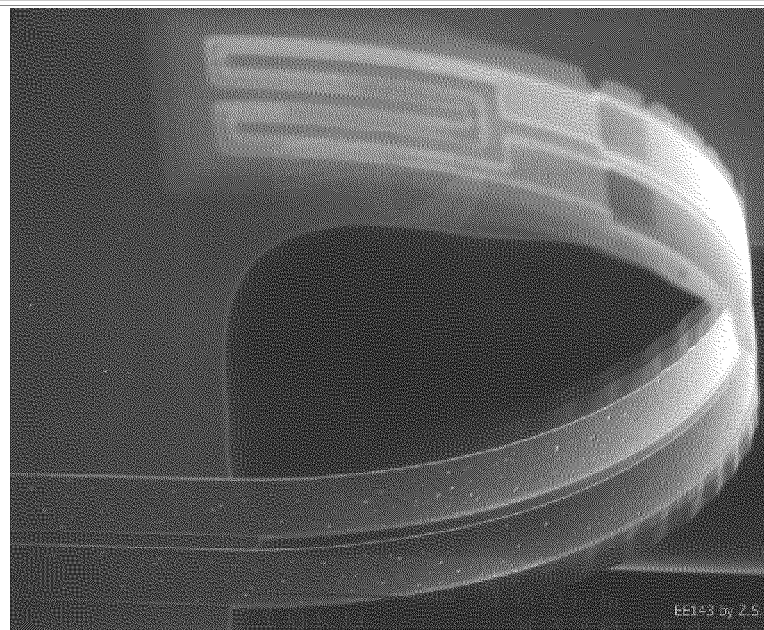
EE143 Chip Overview



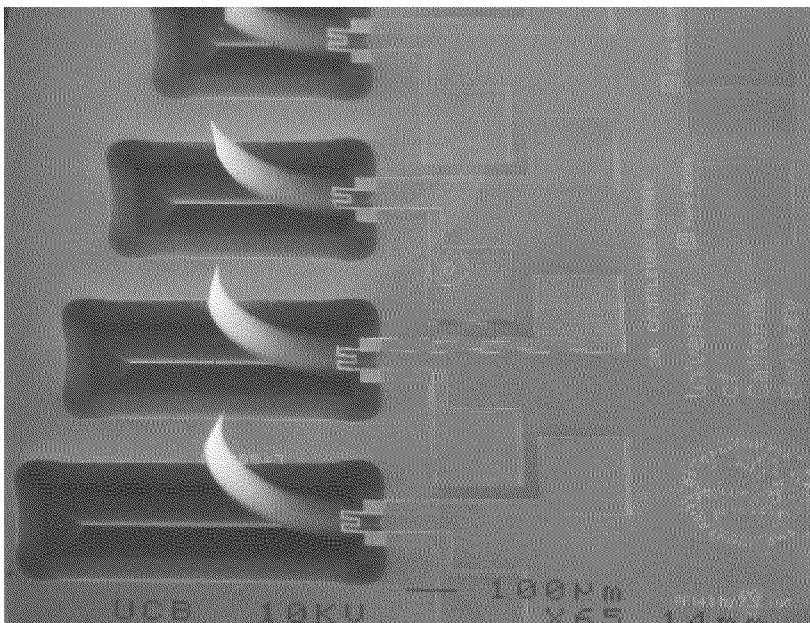
18. Aluminum-SiO₂ Bimorph



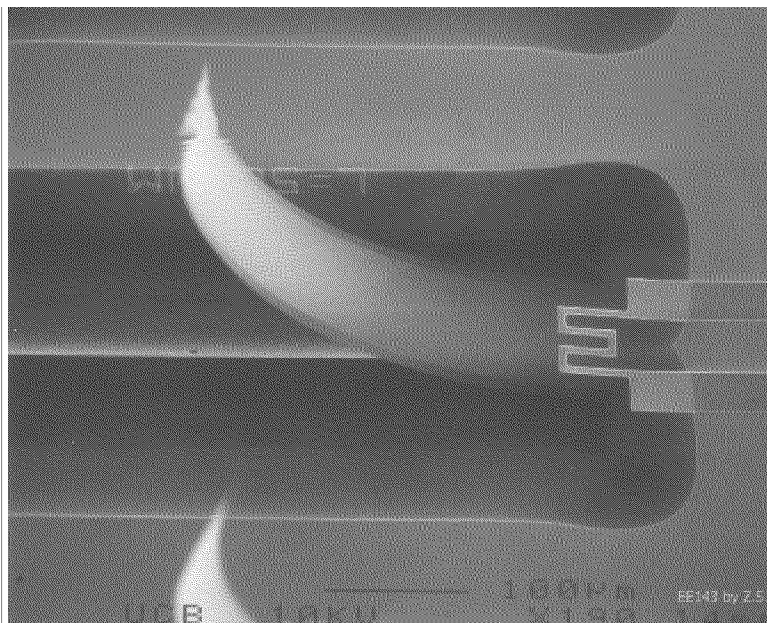
18. Aluminum-SiO₂ Bimorph



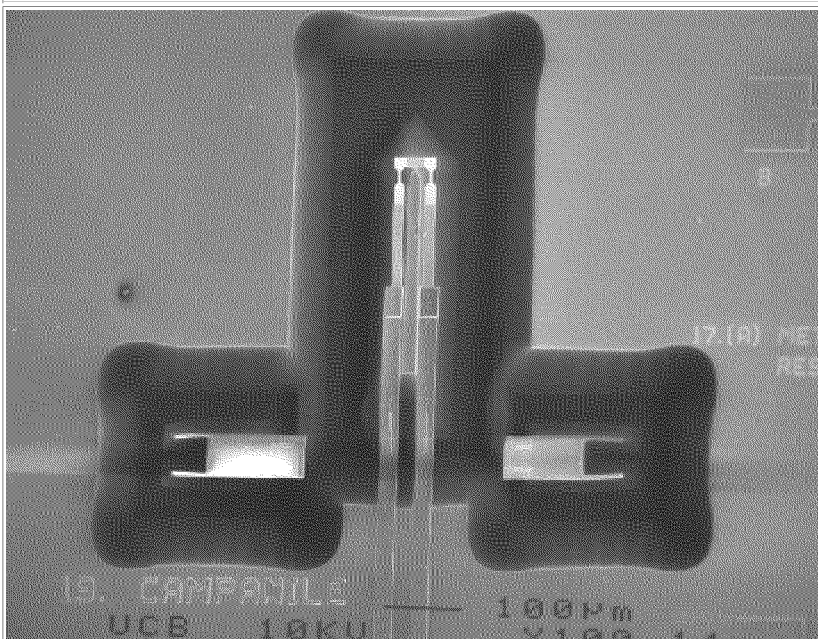
18. Aluminum-SiO₂ Bimorph



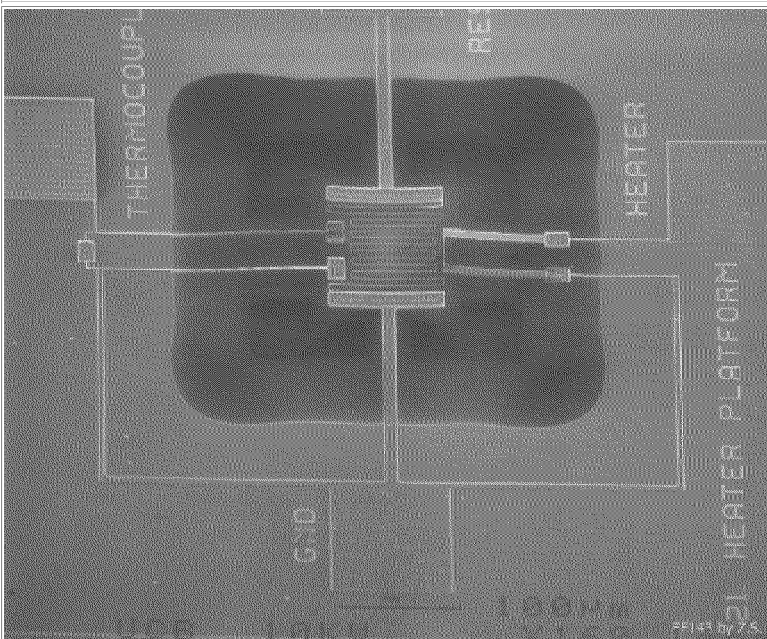
20. Cantilever Array



20. Cantilever Array



19. Campanile



21. Heater Platform

**The MEMS structures were released after 150 cycles of XeF₂ etch (around 7 Hours).*

Last modified on Nov 5, 2003 by Z.S. Luo.

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